



# PixNIL<sup>®</sup> SCS1 and PixNIL<sup>®</sup> SCS2 Application Notes

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**August 2023**

# Standard Film Conditions

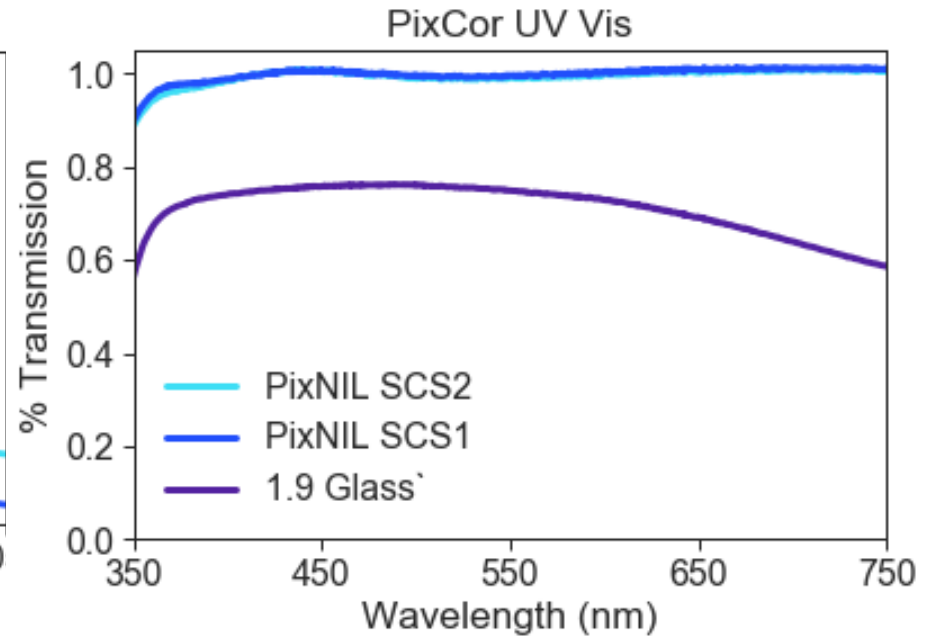
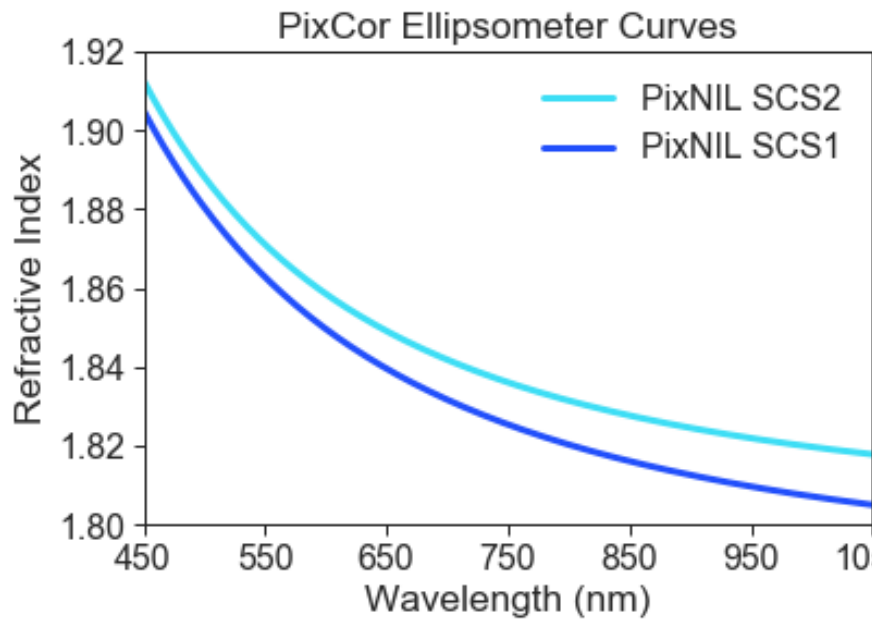
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## **For 300 nm flat film**

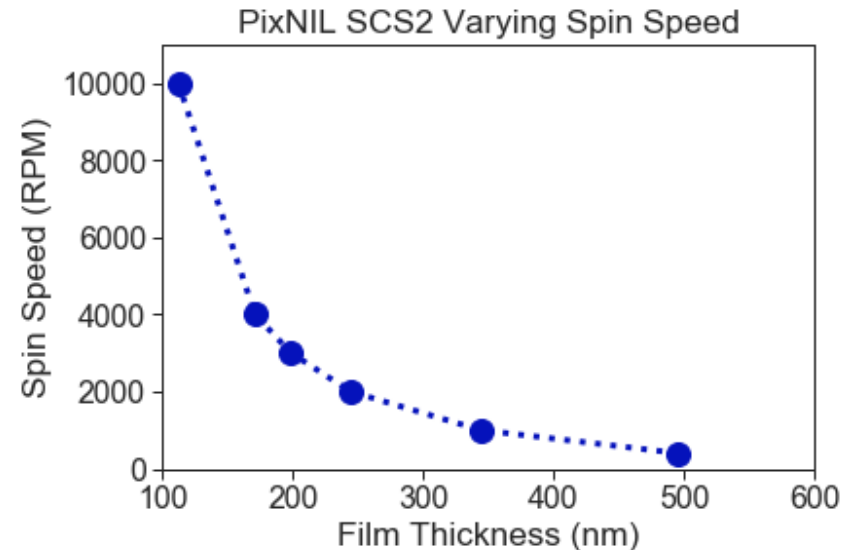
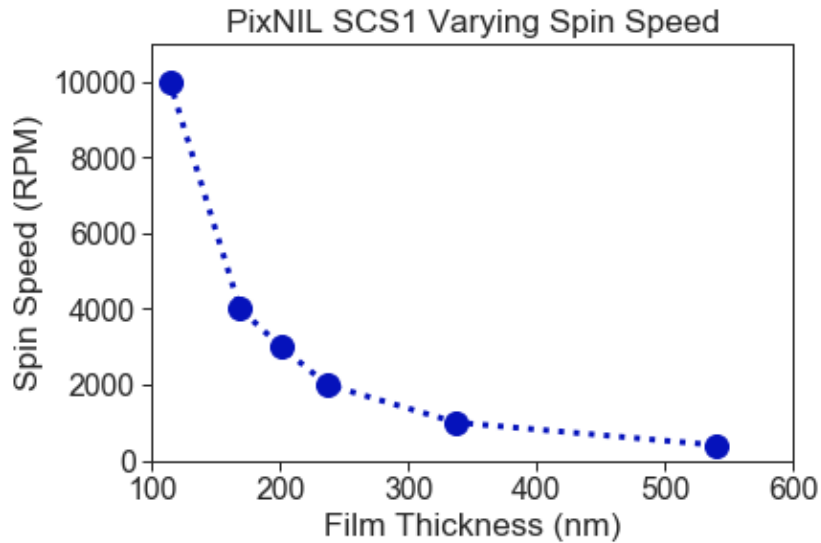
- Spin coat: 2000 rpm / 45 sec
- Prebake: 50 C/ 1 min, hotplate
- Cure:  $320 \text{ mJ/cm}^2 = 2.5 \text{ s} * 128 \text{ mW/cm}^2$ , N2 environment\*
- Postbake: 100 C/ 5 min, oven

\*If curing through a NIL stamp, then N2 environment is not needed.

# Film Data using Recommended Conditions

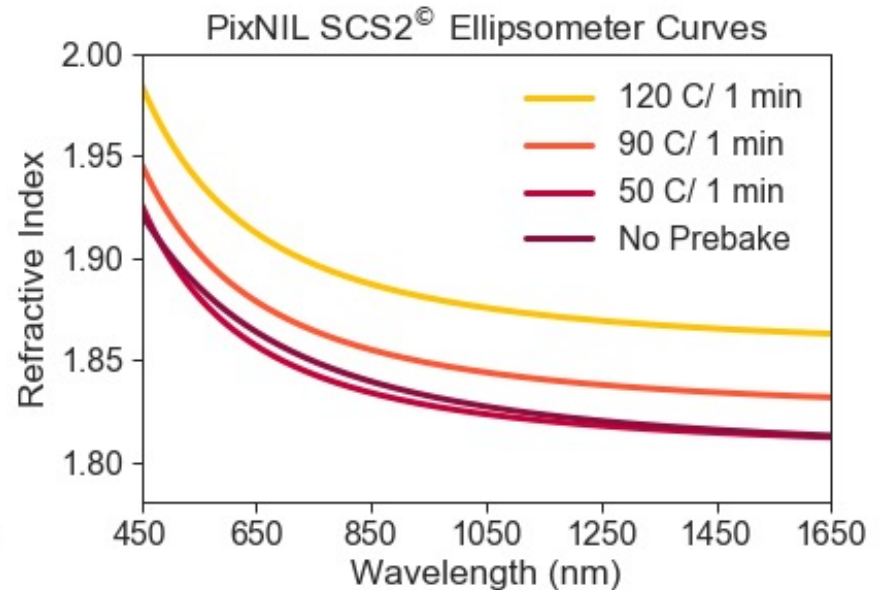
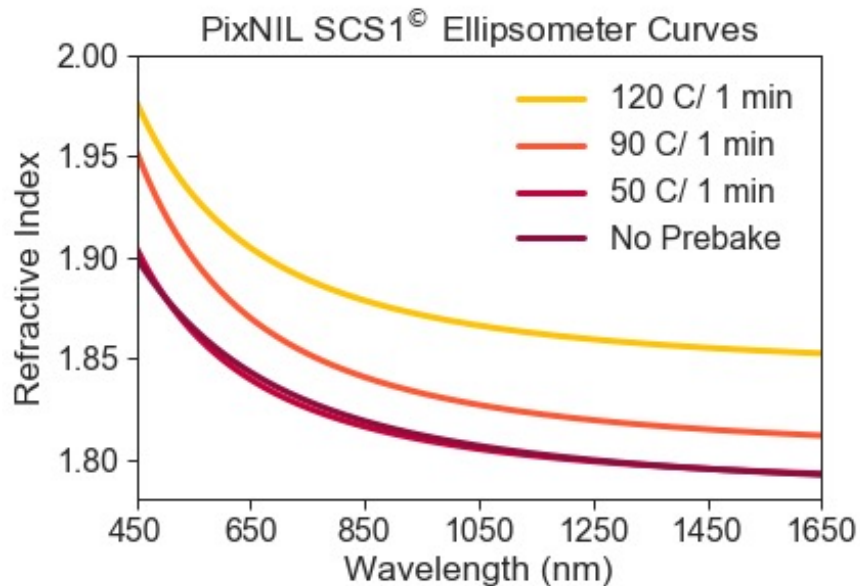


# PixNIL<sup>®</sup> SCS1 and PixNIL<sup>®</sup> SCS2 Spin Curves



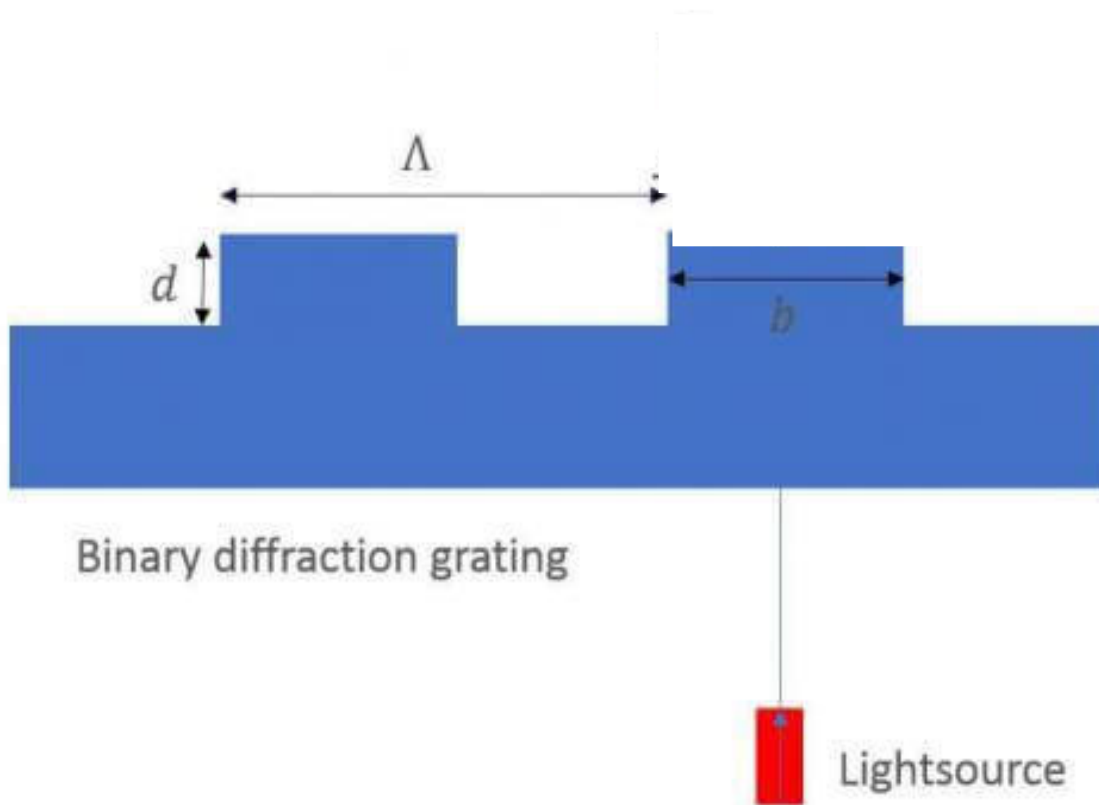
- Spin speeds between 1,000 – 4,000 RPM are recommended and achieve film thicknesses of 150 – 350 nm.

# PixNIL<sup>®</sup> SCS1 and PixNIL<sup>®</sup> SCS2 with Prebakes



- Films are spun at 2000 rpm and postbaked at 100 C/ 5 min while prebakes were varied between no prebake and 120 C / 1 min.
- 50 C/ 1 min prebake is recommended for optimal imprinting.

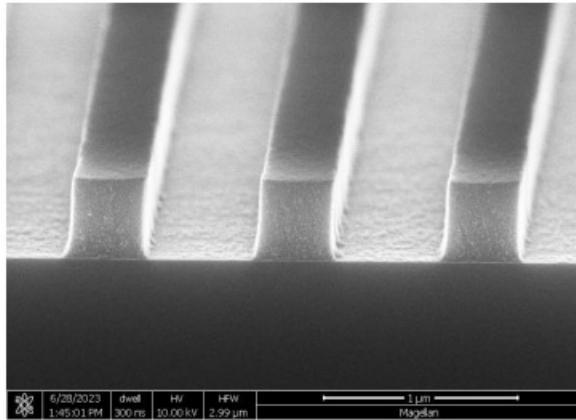
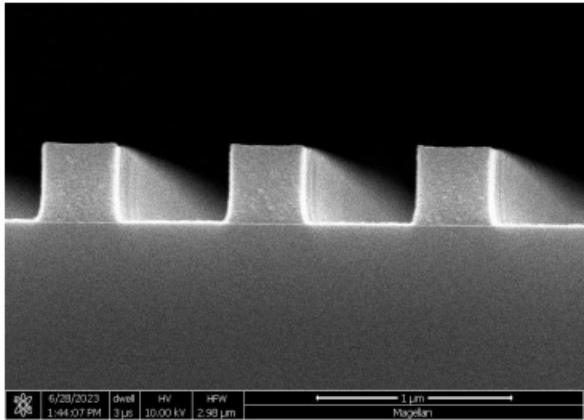
# Residual Film Thickness (RLT) Calculator



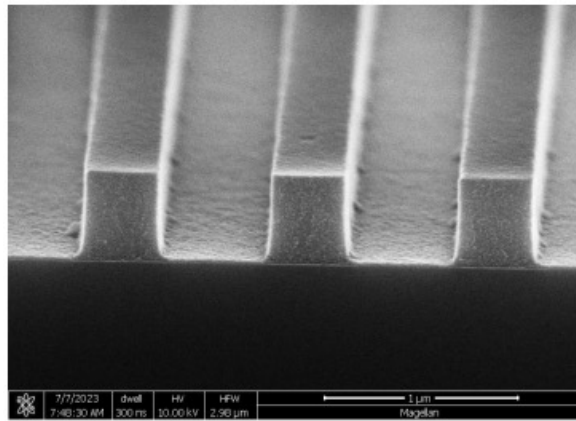
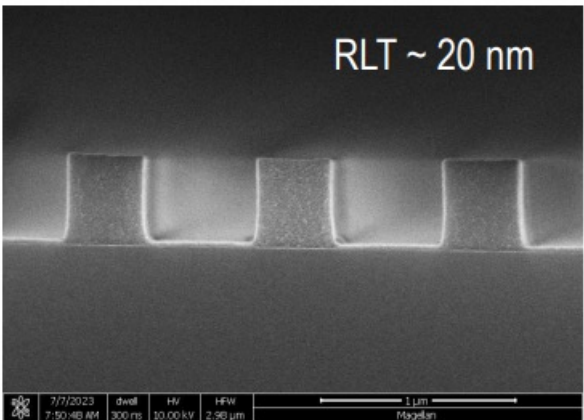
$$RLT = FT - \left( \frac{d * \Lambda}{b} \right)$$

- FT is the initial film thickness
- Calculation works for slanted and binary gratings

# 500 nm binary - PixNIL<sup>®</sup> SCS1

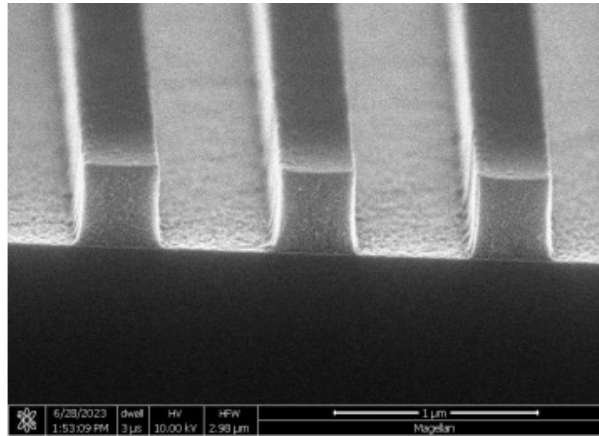
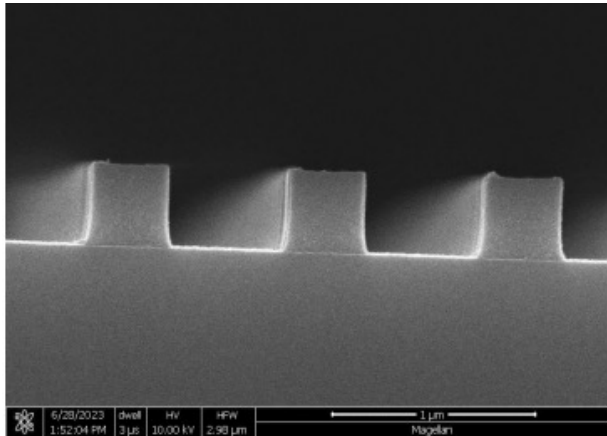


- No prebake, imprint, post bake 100C/ 5 min
- <10 nm RLT

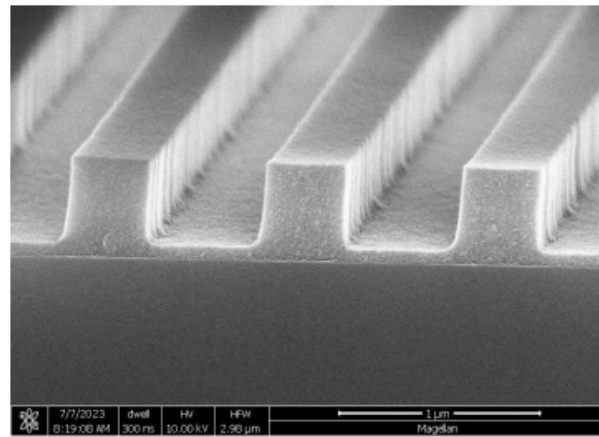
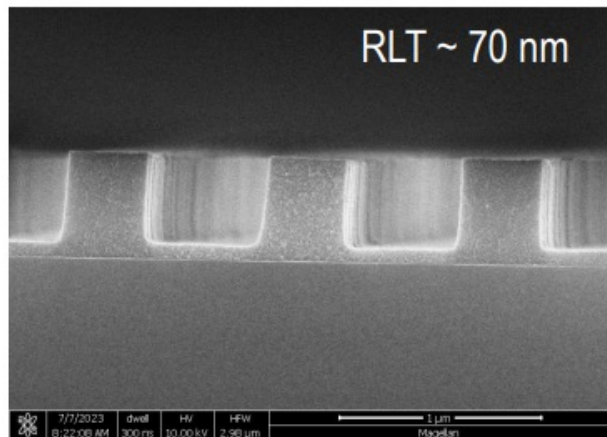


- Prebake 50 C/1 min, imprint, post bake 100C/ 5 min
- ~20 nm RLT

# 500 nm binary - PixNIL<sup>®</sup> SCS2



- No prebake, imprint, post bake 100C/ 5 min
- <10 nm RLT

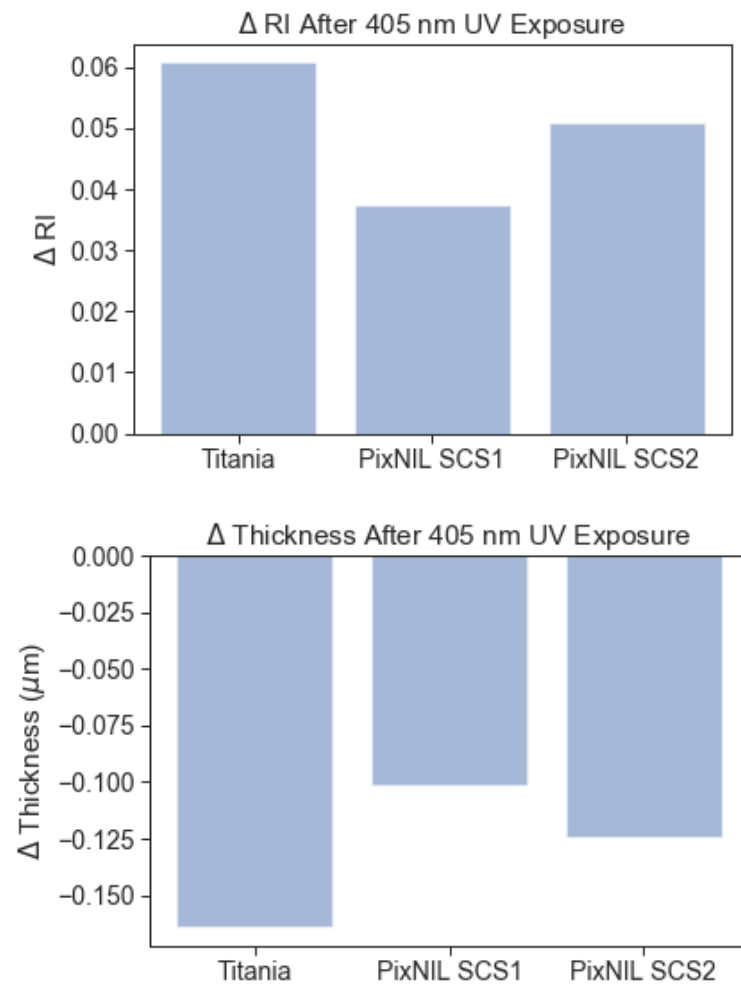
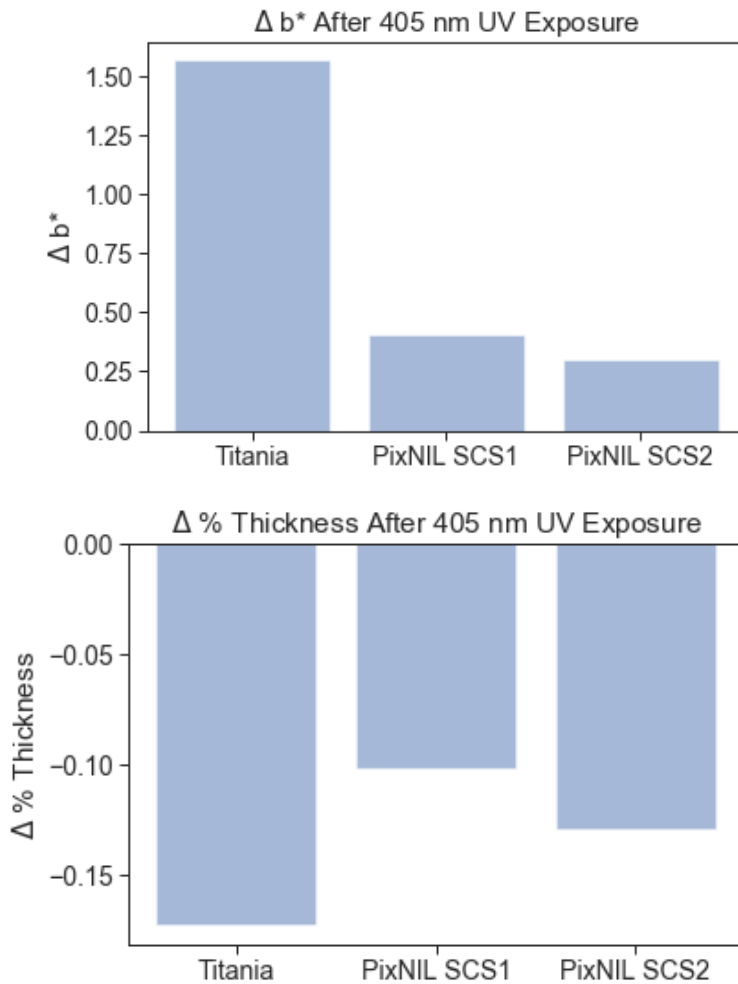


- Prebake 50 C/1 min, imprint, post bake 100C/ 5 min
- ~70 nm RLT

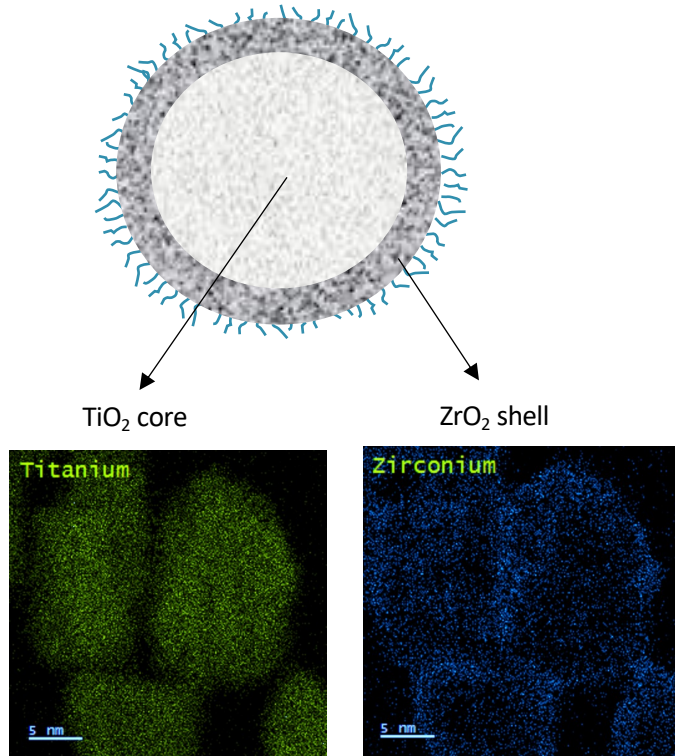


# 1.9 RI NIL PixCor™

UV Exposure  $\Delta\%$ Haze shows no variation between the materials



# PixCor™ Nanocrystals



**Ti and Zr in the same particle**

